

c Molecular beam epitaxy

Quantum wells are grown using Molecular Beam Epitaxy (from the Greek *taxi*, meaning order, and *epi*, meaning over), or MBE. The principle of this physical deposition technique, which was first developed for growing III-V semiconductor crystals, is based on the evaporation of ultra-pure elements of the component to be grown, in a furnace under ultra-high vacuum (where the pressure can be as low as $5 \cdot 10^{-11}$ mbar) in order to create a pure, pollution-free surface. One or more thermal beams of atoms or molecules react on the surface of a single-crystal wafer placed on a substrate kept at high temperature (several hundred °C), which serves as a lattice for the formation of a film called epitaxial film. It thus becomes possible to stack ultra-thin layers that measure a millionth of a millimetre each, *i.e.* composed of only a few atom planes.

The elements are evaporated or sublimated from an ultra-pure source placed in an effusion cell (or Knudsen cell; an enclosure where a molecular flux moves from a region with a given pressure to another region of lower pressure) heated by the Joule effect. A range of structural and analytical probes can monitor film growth *in situ* in real time, particularly using surface quality analysis and grazing angle phase transitions by LEED (*Low energy electron diffraction*) or RHEED (*Reflection high-energy electron diffraction*). Various spectroscopic methods are also used, including Auger electron spectroscopy, secondary ion mass spectrometry (SIMS), X-ray photoelectron spectrometry (XPS) or ultraviolet photoelectron spectrometry (UPS). As ultra-high-vacuum technology has progressed, molecular beam epitaxy has branched out to be applied beyond

III-V semiconductors to embrace metals and insulators. In fact, the vacuum in the growth chamber, whose design changes depending on the properties of the matter intended to be deposited, has to be better than 10^{-11} mbar in order to grow an ultra-pure film of exceptional crystal quality at relatively low substrate temperatures. This value corresponds to the vacuum quality when the growth chamber is at rest. Arsenides, for example, grow at a residual vacuum of around 10^{-8} mbar as soon as the arsenic cell has reached its set growth temperature. The pumping necessary to achieve these performance levels draws on several techniques using ion pumps, cryopumping, titanium sublimation pumping, diffusion pumps or turbomolecular pumps. The main impurities (H_2 , H_2O , CO and CO_2) can present partial pressures of lower than 10^{-13} mbar.